

Tuesday Afternoon, October 20, 2015

Exhibitor Technology Spotlight

Room: Hall 1 - Session EW-TuA

Exhibitor Technology Spotlight Session

4:00pm EW-TuA6 High Efficiency, High Capacity and Economical
"Point of Use" Gas Abatement. *D.K. Prasad*, CS CLEAN SYSTEMS,
Inc.

Air pollution regulations, employee health concerns and growing awareness of toxic agents from semiconductor, industrial and research facilities demand improvements in exhaust gas conditioning. The NOVASAFE dry scrubber reduces the hazards associated with pyrophoric, toxic and corrosive gases and vapors. NOVASAFE effluent gas scrubbers offer an extremely safe and efficient way to treat such process exhausts. The scrubber is a technologically advanced device, containing approximately 10 liters of granulate scrubbing media specific to the process chemistry, and can be used in both production and laboratory and research environments. Operating passively at room temperature, the granulate material reacts on contact with process gases and chemically converts them to non-volatile inorganic solids. NOVASAFE, with its compact form factor, can be integrated with your vacuum pump system to provide a minimal footprint solution. Effluent is abated to sub-TLV levels. The NOVASAFE requires no preventative maintenance, and is replaced and disposed of at its end of life. Granulate is available for many different chemistries, including hydrides, acid gases, metalorganics, etc. making NOVASAFE a cost-effective solution for etch, MOCVD, ALD, ion implant and many other applications.

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